



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Re the Application of

Makoto KOBAYASHI et al.

Application No.: 09/830,434

Filed: April 26, 2001

For: POLISHING PAD AND POLISHING METHOD FOR SEMICONDUCTOR WAFER

Group Art Unit: 3723

Examiner: H. Shakeri

Docket No.: 109352

#11/RCE
M. White
11/26/02

**LARGE ENTITY REQUEST FOR
CONTINUED EXAMINATION UNDER 37 C.F.R. §1.114**

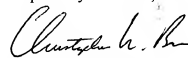
Director of the U.S. Patent and Trademark Office
Washington, D.C. 20231

Sir:

In accordance with the provisions of 37 C.F.R. §1.114, Applicants hereby request continued examination and entry and consideration of the October 28, 2002 submission. The above-identified application was filed on or after June 8, 1995. Thus, entry is proper under 37 C.F.R. §1.114(d).

Attached hereto is our check no. 136399 in the amount of ☒ \$740.00 as payment of the fees set forth in 37 C.F.R. §1.17(e). The Director is hereby authorized to charge any additional fees or credit any overpayment associated with this communication to Deposit Account No. 15-0461. Two duplicate copies of this page are enclosed.

Respectfully submitted,


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Date: November 20, 2002

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